RESPONSE UNDER 37 C.F.R. § 1.116 EXPEDITED PROCEDURE GROUP 2822 PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Docket No: Q85504

Group Art Unit: 2822

Examiner: Tsz K, CHIU

In re application of

Heiji WATANABE, et al.

Appln. No.: 10/519,084

Confirmation No.: 7332

Filed: December 23, 2004

For: SEMICONDUCTOR DEVICE AND ITS MANUFACTURING METHOD RESPONSE UNDER 37 C.F.R. § 1.116 MAIL STOP AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 Sir: In response to the Office Action dated November 18, 2009, please consider the remarks as submitted herewith on the accompanying pages.				
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